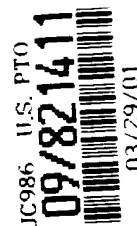


PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Haruo SUNAKAWA, et al. **Examiner:** Unassigned
Serial No: Unassigned **Art Unit:** Unassigned
Filed: Herewith **Docket:** 14463



For: METHOD OF MANUFACTURING A NITROGEN-BASED
SEMICONDUCTOR SUBSTRATE AND A SEMICONDUCTOR ELEMENT
BY USING THE SAME

Dated: March 29, 2001

Assistant Commissioner for Patents
United States Patent and Trademark Office
Washington, D.C. 20231

CLAIM OF PRIORITY

Sir:

Applicants in the above-identified application hereby claim the right of priority
in connection with Title 35 U.S.C. § 119 and in support thereof, will submit in due course a
certified copy of Japanese Patent Application No. 91963/2000, filed on March 29, 2000.

Respectfully submitted,

Paul J. Esatto, Jr.

Registration No.: 30,749

Scully, Scott, Murphy & Presser
400 Garden City Plaza
Garden City, New York 11530
(516) 742-4343

CERTIFICATE OF MAILING BY "EXPRESS MAIL"

Express Mailing Label No.: EL835917832US
Date of Deposit: March 29, 2001

I hereby certify that this correspondence is being deposited with the United States
Postal Service "Express Mail Post Office to Addressee" service under 37 C.F.R. § 1.10 on the
date indicated above and is addressed to the Assistant Commissioner for Patents and
Trademarks, Washington, D.C. 20231 on March 29, 2001.

Dated: March 29, 2001

Michelle Mustafa

G:\nec\995\14463\misc\14463.claimprior